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Docket No.: 80585(302765)
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Toshiro Yamada et al.

Application No.: 10/520,272

Confirmation No.: 4526

Filed: January 14, 2005

Art Unit: 1792

For: METHOD OF DRY ETCHING, DRY
ETCHING GAS AND PROCESS FOR
PRODUCING PERFLUORO-2-PENTYNE

Examiner: S. Ahmed

AMENDMENT AFTER FINAL ACTION UNDER 37 C.F.R. 1.116

MS AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

INTRODUCTORY COMMENTS

In response to the Office Action dated August 12, 2008, finally rejecting claims 1, 2, 6 and 7, please amend the above-identified U.S. patent application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 3 of this paper.